

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Amended) A method for manipulating a first plate in a MEMS device relative to a second plate in a MEMS device, the method comprising:
  - providing a first actuator and a second actuator disposed above a base layer;
  - providing the first plate supported by a first pivot, wherein the first plate is disposed above the first actuator and the first pivot is disposed above the base layer between the first actuator and the second actuator;
  - providing a second plate supported by a second pivot, wherein the second plate is disposed above the second actuator and the second pivot is disposed above the base layer;
  - activating the second actuator to cause the second plate to impact the first plate;
  - wherein the first plate comprises a mirror, and wherein the second plate comprises a mirror.
2. (Original) The method of claim 1, wherein the impact is a first impact, the method further comprising:
  - deactivating the second actuator, wherein the second plate moves away from the first plate; and
  - reactivating the second actuator to cause the second plate to impact the first plate for a second time.
3. (Original) The method of claim 1, the method further comprising:
  - activating the first actuator to create an actuator force on the first plate, wherein the actuator force on the first plate encourages the first plate to deflect toward the second plate.
4. (Cancelled)

5. (Original) An apparatus adapted for encouraging a structural plate in a MEMS device to deflect toward a static position, the apparatus comprising:

- a base layer;
- a first pivot and a second pivot disposed on the base layer;
- a first structural plate supported by the first pivot and disposed above the base layer, wherein the first structural plate is deflected away from the static position;
- a second structural plate supported by the second pivot and disposed above the base layer; and

wherein the second structural plate is movable to generate a physical force, and wherein the physical force encourages the first structural plate to move toward the static position.

6. (Original) The apparatus of claim 5, the apparatus further comprising:

- a first actuator for deflecting the first structural plate;
- a second actuator for deflecting the second structural plate; and
- wherein the first and second actuators are electrically coupled.

7. (Original) The apparatus of claim 5, wherein the first actuator is operable to deflect the first structural plate toward the base layer at a position away from the second structural plate, the apparatus further comprising:

- a third actuator operable to deflect the first structural plate toward the base layer at a position near the second structural plate.

8. (Original) A MEMS device adapted for overcoming a stiction force incident at a stop position, the device comprising:

- a base layer;
- a first plate supported by a first pivot, wherein the first plate is disposed above the base layer and the first pivot is disposed on the base layer;
- a second plate supported by a second pivot, wherein the second plate is disposed above the base layer and the second pivot is disposed on the base layer;

a first actuator for deflecting the first plate and a second actuator for deflecting the second plate, wherein the first actuator is electrically connected to the second actuator; and  
wherein energizing the first and second actuators causes the first plate to deflect away from the second plate and the second plate to deflect away from the first plate.

9. (Amended) A method for generating a physical force in an electro-mechanical device, the method comprising:

providing a base layer;  
providing a first pivot and a second pivot disposed on the base layer;  
providing a first structural plate supported by the first pivot and disposed above the base layer;  
providing a second structural plate supported by the second pivot and disposed above the base layer; and  
deflecting the second structural plate to contact the first structural plate;  
wherein deflecting the second structural plate is caused, at least in part, by a restorative force between the second structural plate and the second pivot.

10. (Cancelled)

11. (Original) The method of claim 9, the method further comprising;  
providing an actuator disposed on the base layer and under the second structural plate; and  
activating the actuator to create an electric field force, wherein the deflecting the second structural plate is caused, at least in part, by the electric field force.

12. (Original) The method of claim 9, the method further comprising:  
providing a first actuator disposed on the base layer and under the first structural plate;  
providing a second actuator disposed on the base layer and under the second structural plate; and

activating the first actuator, wherein the first actuator creates a first electric field force;

activating the second actuator, wherein the second actuator creates a second electric field force, wherein the deflecting the second structural plate is caused, at least in part, by a combination of the second electric field force and a restorative force between the second structural plate and the second pivot.

13. (Original) The method of claim 9, wherein the deflecting the second structural plate comprises moving the second structural plate into contact with the first structural plate.

14. (Original) The method of claim 9, wherein a stiction force exists at a point of contact between the first structural plate and the base layer, and wherein a combination of a restorative force between the first structural plate and the first pivot and the disturbance in the molecule build-up or adhesion force is sufficient to overcome the stiction force.

15. (Original) The method of claim 9, the method further comprising:  
providing an actuator disposed on the base layer and under the second structural plate; and

activating the actuator to create an electric field force, wherein the deflecting the second structural plate is caused, at least in part, by the electric field force, and wherein a first impact occurs between the first structural plate and the second structural plate;

deactivating the actuator, wherein the second structural plate moves away from the first structural plate; and

reactivating the actuator to create the electric field force, wherein a second impact occurs between the first structural plate and the second structural plate.

16. (Cancelled)